



**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicants: T. UCHIDA, et al.  
Serial No. 10/069,404  
Filed: MAY 6, 2002  
For: POLISHING MEDIUM FOR CHEMICAL-MECHANICAL  
POLISHING, AND POLISHING METHOD  
Group AU: 1765  
Examiner: Lynette T. Umez Eronini  
Confirm. No: 3597

**AMENDMENT AFTER FINAL REJECTION**

**Mail Stop: AF – FEE**  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

February 26, 2007

Sir:

In response to the Office Action mailed August 25, 2006, the period of response having been extended for three (3) months by the attached Petition for Extension of Time, please amend the above-identified application as listed in the following, and as set forth on the following pages:

AMENDMENTS TO THE CLAIMS; and

REMARKS are included following the amendments.